

# **IMFEDK 2020 Satellite event**

**The 2020 International Meeting for Future of Electron Devices, Kansai**  
**November 27, 2020 Online**

## **IMFEDK 2020**

**International Meeting for Future of Electron Devices, Kansai**

November 27, 2020

Online (Kyoto Institute of Technology)

Sponsor:

IEEE Electron Device Society, Kansai Chapter



# IMFEDK 2020 Satellite event Poster Session

**Short Presentation: 9:05 – 10:05 Nov. 27 2020**

**Poster Presentation: 12:30 – 14:00 Nov. 27 2020**

**P-1 RF Extraction Method for Off-State Equivalent Circuit in PD-SOI MOSFETs**

Jinwook Kuk, Seonghearn Lee

Department of Electronic Engineering, Hankuk University of Foreign Studies, Korea

**P-2 Phase Change Random Access Memory Using Cu<sub>2</sub>GeTe<sub>3</sub>**

Shihori Akane<sup>1</sup>, Isao Horiuchi<sup>2</sup>, Mutsumi Kimura<sup>1</sup>

1.Ryukoku University, 2.KOA Corporation

**P-3 A mist CVD-derived ferroelectric Hf<sub>1-x</sub>Zr<sub>x</sub>O<sub>2</sub> films with possible operation for non-volatile analog memory**

Yuki Fujiwara, Junya Onishi, Hiroyuki Nishinaka, Masahiro Yoshimoto, and Minoru Noda  
Kyoto Inst. Tech.

**P-4 Simulation of graphene photodetectors incorporating the photo-gating effect**

Shingo Aida, Matsuto Ogawa, and Satofumi Souma

Department of Electrical and Electronic Engineering, Kobe University

**P-5 Ferroelectric gate thin film transistor using oxide semiconductor Ga-Sn-O**

Tomoki Fukui, Kouki Nakagawa, Mutsumi Kimura

Ryukoku university

**P-6 Improved Interfaces of high-K ZrO<sub>2</sub> and AlGaN via ex-situ MOVPE regrowth**

Itsuki Nagase<sup>1</sup>, Joel T. Asubar<sup>1</sup>, Rui Shan Low<sup>1</sup>, Shun Urano<sup>1</sup>, Shunsuke Kamiya<sup>1</sup>, Ali Baratov<sup>1</sup>, Hirokuni Tokuda<sup>1</sup>, Akio Yamamoto<sup>1</sup>, and Masaaki Kuzuhara<sup>2</sup>

1.University of Fukui, 2.Kwansei Gakuin University

**P-7 GPU-accelerated Monte Carlo simulation of quasi-ballistic phonon transport in Si**

Yuma FUJITA, Yuhei SUZUKI, and Yoshinari KAMAKURA

Faculty of Information Science and Technology, Osaka Institute of Technology

**P-8 Ferroelectric thin film synapses for neuromorphic devices**

Yuma ISHISAKI<sup>1</sup>, Hiroki UMEMURA<sup>1</sup>, Daiki MATSUKAWA<sup>1</sup>, Eisuke TOKUMITSU<sup>2</sup>, Kenichi HAGA<sup>3</sup>, Toshihiro DOI<sup>3</sup>, Mutsumi KIMURA<sup>1</sup>

1. Ryukoku University, 2. Japan Advanced Institute of Science and Technology,  
3. Mitsubishi Materials Corporation,

**P-9 Epitaxial Growth of ZnO Thin Films on Flexible Substrates and Characteristics of Optical Properties by Bending**

Yuta Arata, Hiroyuki Nishinaka, Masahiro Yoshimoto

Kyoto Institute of Technology

**P-10 Simulation of spin-dependent conduction characteristics in graphene nanoribbon quantum dot FET for realization of spin qubit**

Naruki Sasaki, Matsuto Ogawa, and Satofumi Souma

Department of Electrical and Electronic Engineering, Kobe University

**P-11 Dependence of thermoelectric performance on annealing temperature for GTO thin film device**

Yamamoto Yuhei, Tatsuya Aramaki, Ryo Ito, Mutsumi Kimura  
Ryukoku university

**P-12 Effect of Post-Metallization Annealing on Properties of ZrO<sub>2</sub>/regrown-AlGaIn/GaN structures**

Shun Urano<sup>1</sup>, Joel T. Asubar<sup>1</sup>, Itsuki Nagase<sup>1</sup>, Rui Shan Low<sup>1</sup>, Shunsuke Kamiya<sup>1</sup>, Ali Baratov<sup>1</sup>, Hirokuni Tokuda<sup>1</sup>, Akio Yamamoto<sup>1</sup>, and Masaaki Kuzuhara<sup>2</sup>

1. University of Fukui, 2. Kwasei Gakuin University

**P-13 Characterization of mist-CVD deposited Al<sub>2</sub>O<sub>3</sub> films on AlGaIn/GaN heterostructures**

Tomohiro Motoyama<sup>1</sup>, Kenta Naito<sup>1</sup>, Yusui Nakamura<sup>1</sup>, Zenji Yatabe<sup>1</sup>, Rui Shan Low<sup>2</sup>, Itsuki Nagase<sup>2</sup>, Ali Baratov<sup>2</sup>, Hirokuni Tokuda<sup>2</sup>, Masaaki Kuzuhara<sup>3</sup>, Joel T. Asubar<sup>2</sup>

1. Kumamoto University, 2. University of Fukui, 3. Kwasei Gakuin University

**P-14 Investigation of oxide semiconductor thin film synapse using STDP learning method**

Tetsuya KATAGIRI, Daiki YAMAKAWA, Kenta YATIDA, Kazuki MORIGAKI, Mutsumi KIMURA  
Ryukoku University

**P-15 Effect of recoil-implanted N atoms on defect formation in Mg-implanted GaN**

K. C. Herbert<sup>1</sup>, K. Shibata<sup>1</sup>, J. T. Asubar<sup>2</sup>, M. Kuzuhara<sup>1</sup>

1. Kwasei Gakuin University, 2. University of Fukui

**P-16 Growth of Rhombohedral Indium Oxide Thin Films on LiTaO<sub>3</sub> Substrate for Fabrication of Lattice Matched Indium Gallium Oxide Power Devices**

Kazuki Shimazoe, Hiroyuki Nishinaka, Yuta Arata, Yusuke Ito, and Masahiro Yoshimoto  
Kyoto Institute of Technology, Department of Electronics

**P-17 Stacked cross-point memory of synaptic elements using IGZO thin film**

Etsuko Iwagi<sup>1</sup>, Takumi Tsuno<sup>2</sup>, Mutsumi Kimura<sup>1,2</sup>

1. Ryukoku university, 2. Nara Institute of Science and Technology

**P-18 Consideration of scattering process in nanoscale device simulation based on top of barrier model**

Ren Tanaka, Matsuto Ogawa, and Satofumi Souma  
Department of Electrical and Electronic Engineering, Kobe University

**P-19 Brain type system using IGZO thin film synapses**

Yuki Onishi<sup>1</sup>, Yuki Shibayama<sup>1</sup>, Daiki Yamakawa<sup>1</sup>, Hiroya Ikeda<sup>2</sup>, Yasuhiko Nakashima<sup>2</sup>, Mutsumi Kimura<sup>1,2</sup>

1. Ryukoku University, 2. Nara Institute of Science and Technology

**P-20 Deposition and Characteristics of lead-free Cs<sub>3</sub>Cu<sub>2</sub>(Cl<sub>1-x</sub>I<sub>x</sub>)<sub>5</sub> (0 ≤ x ≤ 1) thin films**

Keisuke Watanabe, Hiroyuki Nishinaka, Masahiro Yoshimoto  
Kyoto Institute of Technology

**P-21 Automation of characteristic measurement of amorphous oxide semiconductor memristors and their effects**

Ryo SUMIDA, Ayata KURASAKI, Daisuke MAKIOKA, Mutsumi KIMURA  
Ryukoku university

**P-22 Biological environment imitation experiment of artificial retina using thin film device**

Naoya Naito<sup>1</sup>, Kouhei Toyoda<sup>1</sup>, Yoshio Okano<sup>2</sup>, Mutsumi Kimura<sup>1</sup>

1. Ryukoku university, 2. WetLab corporation